



WAFER FOUNDRY FACILITY AND BUILDING FOR SALE

2108 BERING DRIVE, BLDG B. SAN JOSE, CA 95131



MOOV TECHNOLOGIES INC.

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701 BRAZOS ST. SUITE 930. AUSTIN, TEXAS 78701

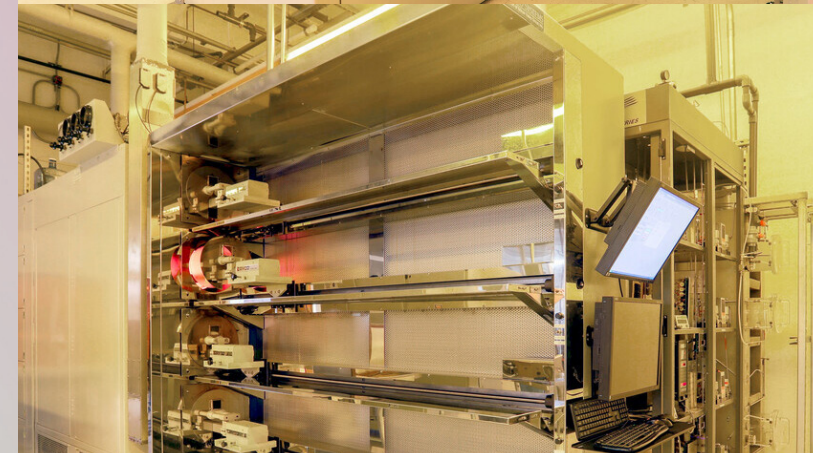
DAVE ARKOW DARKOW@MOOV.CO

WAFER FOUNDRY HIGHLIGHTS

PURE PLAY 150 MM SEMICONDUCTOR WAFER FOUNDRY

DESCRIPTION: **150MM SEMICONDUCTOR WAFER FOUNDRY / R&D FACILITY**
 FAB CONSTRUCTION YEAR: **2009**

- WAFER FOUNDRY.CO owns and operates a Bipolar, BiCMOS, MEMS, etc. 150mm and 100mm Semiconductor Wafer Foundry.
- The wafer foundry has capacity to support a potential run rate of 10,000 wafers per year, with potential revenue of \$10M/year within two years.
- Currently, the wafer foundry is the only 150mm Pure-play Bipolar, BiCMOS, MEMS, etc. wafer foundry in Silicon Valley and can be repurposed for GaN and SiC.
- The installed wafer fabrication equipment and infrastructure is compatible with many legacy technologies for aviation, space, communications, automotive, biomedical, MEMS, defense, analog, digital and RF ICs and many types of discrete semiconductors.



INVESTMENT HIGHLIGHTS**5,998 SF INDUSTRIAL/R&D CONDO FOR SALE**

LOCATION: 2108 BERING DRIVE, BLDG. B, SAN JOSE, CALIFORNIA 95131

BUILDING: 5,998 SF INDUSTRIAL / R&D CONDOMINIUM

LOT SIZE: 13,225 SF | 0.30 AC

YEAR BUILT: 1977

- 2108 Bering Drive, Bldg. B, San Jose is an opportunity to purchase a 5,998 SF Industrial / R&D condo fully built out as a 150mm semiconductor wafer foundry. The property is available for sale or for lease with the equipment/facility being offered for sale or lease as well.
- The property has 1 roll-up door with a building clear height of 16ft. This is a very rare Owner User opportunity to purchase or lease a 150mm semiconductor wafer foundry in a market with very high barriers to entry. The property is strategically positioned on Bering Drive, situated between Charcot Avenue and E Brokaw Road with immediate access to Hwy 101, HWY 87, and HWY 880 and within 1 mile from San Jose airport.



FACILITY & EQUIPMENT LIST (PART I)

MANUFACTURING EQUIPMENT

- a. Diffusion Furnace Banks, 1x2 200mm / MRL / High Temperature Silicon Carbide Tubes – Optional; 2x4 200mm THERMCO –Optional
- b. Stepper (1) Canon 2500i2
- c. Spin Coater SVG 8100
- d. Ion Implanter (2) Varian 300XP
- e. Plasma Etchers (4) Lam Research, 409,509
- f. LPCVD (4) Protemp -Custom build
- g. Vacuum Sputtering Deposition MRC -903 -cryo pumped
- h. Capacity of Tool Line ~1,000 wafers/month (6L)

CLEANROOMS

- a. Cleanroom Configuration Bay and chase
- b. Cleanroom Class 100 1,100 sf
- c. Cleanroom Class 1000 3,100 sf
- d. 2 Additional Clean Rooms ~350 sf

SUPPORT INFRASTRUCTURE

- a. Power 208V, 3ph, 600 Amp
- b. Incoming Water city water
- c. Wastewater Treatment AWN
- d. DI Water 100 gal/h
- e. Gas N/A
- f. Exhaust Yes
- g. Bulk and Generated Gases N2 generator
- h. Backup Generators N/A
- i. Cooling Chillers
- j. Ceiling Heights 16 ft.

OPERATING STATUS

- a. Facility Commenced Production 2010
- b. Products Bipolar and BICMOS >1um

FACILITY & EQUIPMENT LIST (PART 2)

CLEANROOM EQUIPMENT

All equipment is 4-inch wafers 6-inch configurable, with a few tools also configurable for 8-inch wafers.

THE TOOLSET INCLUDES:

- Sputter Deposition Systems 5pc
- E-Beam Evaporator
- High Temperature Furnaces, Silicon carbide tubes
- LPCVD capabilities Si₃N₄, a:Si, LTO, POCl₃
- PECVD AMAT 3000
- Plasma Oxygen Asher
- Solvent Bench
- Acid/Base Benches
- Photo-Resist Spinners
- Rinse/Dryer Tools
- IPA dryer
- Ellipsometers
- Programmable Ovens
- 1X Aligners, 2 sets
- 5X Stepper (0.45um)
- Spin coaters Track
- Plasma etchers Lam 409 and 509 (4+)
- Plasma etchers Lam 901, 903
- EPI Reactors AMAT 7600 -not installed -warehouse
- EPI reactor First Nano - within wafer fab, in process to be installed
- Ion Implanters 2pc 300XP
- Laser trimers LTX 80 Win 44 2pc
- Dicing saws MA1006, MA1100 4pc
- Dicing Saw K&S
- SEM Hitachi
- HP 4145B Semiconductor parameter analyzer
- Tektronix Curve tracers
- Fluke 8840A, Keithley multimeters
- Wire bonders, die attach

TECHNOLOGIES: BIPOLAR, BICMOS, CMOS, MEMS

APPROX. PRODUCTION CAPACITY: ~1000 WPM

DESIGN RULE: 0.45 UM (5X STEPPER)

SEVERAL CLEAN ROOMS: CLASS ~100 AND 1000 CLEANROOM

WAREHOUSE MACHINE SHOP: LOTS OF SEMICONDUCTOR PROCESSING EQUIPMENT

CENTRALIZED UTILITIES

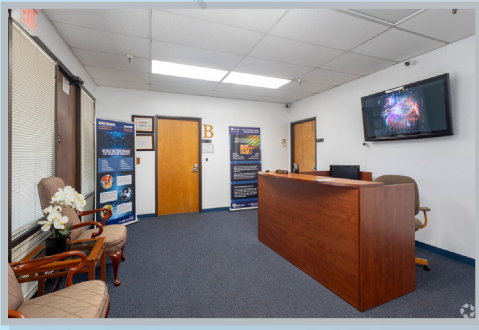
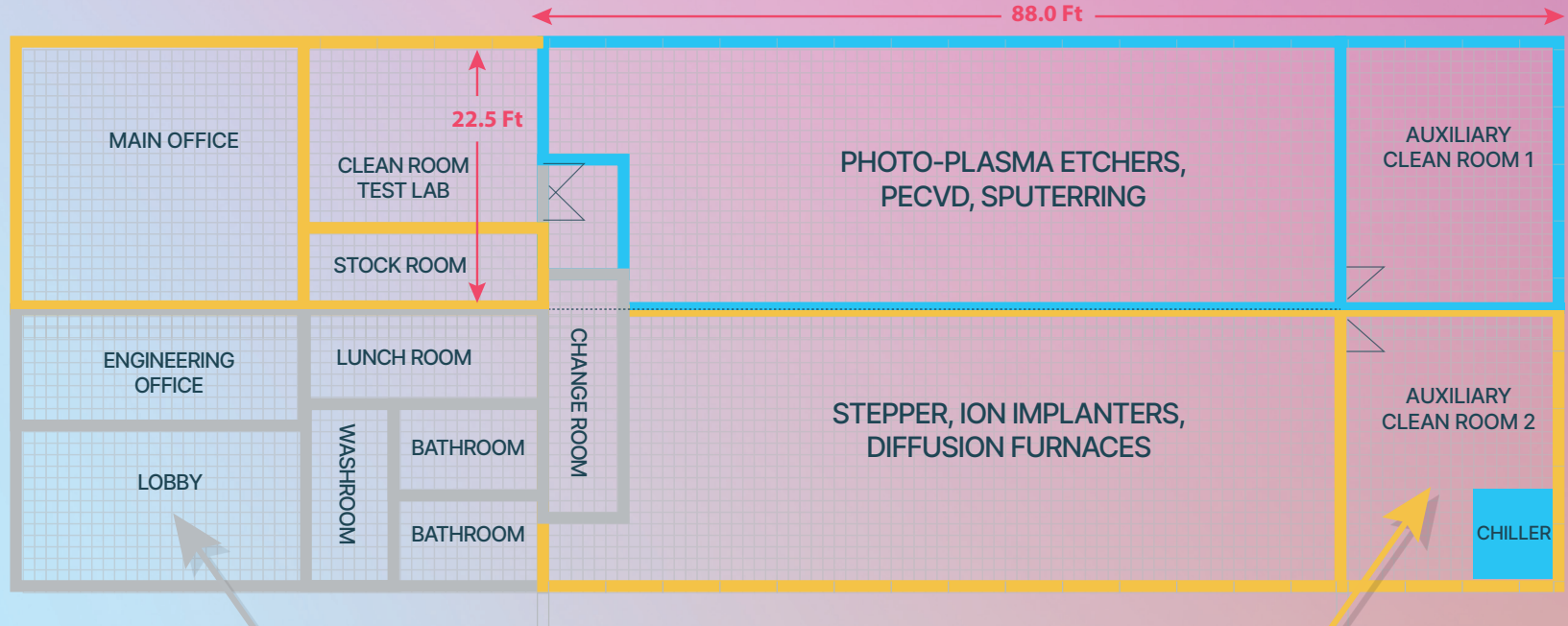
- DI Water
- Nitrogen Generator
- Comprehensive Piped Waste Management System AWN
- Compressed Air (multiple generators)
- Vacuum
- Chilled Water (multiple sources)
- Fire and Security Monitoring System
- Dedicated Power Supply (480 V, 208 V, 3 phase)
- High-Speed Internet

PROCESS CAPABILITIES:

- Photolithography
- Wet chemical processes
- Dry Silicon etching
- Thermal Oxidation
- Ion Implantation & Diffusion
- Thermal Annealing
- Evaporation
- Sputtering
- Plasma Asher
- Mega Sonic Cleaning
- Ultrasonic cleaning
- Liftoff
- Film thickness measurement
- SEM

FLOOR PLAN

BUILDING B



Scale = 1x1 sq Ft.







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ABOUT MOOV

We're more than the world's first real-time digital equipment marketplace. We're a global ecosystem of buyers, sellers, service, logistics, and insurance providers, dedicated to a reliable, sustainable secondary market for semiconductor manufacturing assets.

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